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## \*BIBDATASHEET\*

Bib Data Sheet

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SERIAL NUMBER 10/657,429	FILING DATE 09/08/2003 RULE	CLASS 250	GROUP ART UNIT 2881	ATTORNEY DOCKET NO. NECF 17.638B
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## APPLICANTS

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## \*\* CONTINUING DATA \*\*\*\*

This application is a DIV of 09/641,125 08/16/2000 PAT 6,645,676 *a,2.*

## \*\* FOREIGN APPLICATIONS \*\*\*\*

JAPAN 11-232358 08/19/1999 *a,2.*

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 12/15/2003

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY	SHEETS	TOTAL	INDEPENDENT
35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	JAPAN	DRAWING 9	CLAIMS 1	CLAIMS 1
Verified and Acknowledged	<i>a,2.</i> Examiner's Signature	Initials			

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## TITLE

Electron beam exposure mask, electron beam exposure method, method of fabricating semiconductor device, and electron beam exposure apparatus

FILING FEE	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue )
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